



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Wang, et al.

Serial No.: 10/800,112

Confirmation No.: 8920

Filed: March 12, 2004

For: Method of Depositing an  
Amorphous Carbon Film for  
Metal Etch Hardmask  
Application

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Group Art Unit: 1765

Examiner: Mahmoud Dahmene

MAIL STOP AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on <u>February 6, 2006</u> , with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.	
February 6, 2006 Date	 Brian K. Hrna

STATEMENT OF COMMON OWNERSHIP

The present application (Serial No. 10/800,112; hereinafter the "Application"), and United States Patent Application Serial No. 10/438,638 (Patent Publication No. 2004/0229470), *Rui et al*, were, at the time the invention of the Application was made, owned by the same person, or subject to an obligation of assignment to the same person, Applied Materials, Inc.

Respectfully submitted,

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